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INTERNATIONAL PRELIMINARY EXAMINATION REPORT

(PCT Article 36 and Rule 70)

Applicant's or agent's file reference		
60274-080 International application No.	FOR FURTHER ACTION	See Notification of Transmittal of International Preliminary Examination Report (Form PCT/IPEA/416
i international application No.	International filing date (day/mon	nth/year) Priority date (day/month/year)
PCT/US03/04941	18 February 2003 (18.02.2003)	
International Patent Classification (IPC)	or national classification and IPC	26 July 2002 (26.07.2002)
IPC(7): B01D 53/06 and US Cl.: 96/12		
Applicant	9, 101, 140, 134, 93/113	
DOURR ENVIRONMENTAL INC.		
		·
 This international preliming Examining Authority and 	nary examination report has been is transmitted to the applicant ac	n prepared by this International Preliminary coording to Article 36.
2. This REPORT consists of		
This report is also acc	Companied by ANNIEVED	
which have been ame	ended and are the basis for this r	sheets of the description, claims and/or drawings report and/or sheets containing rectifications made
before this Authority	(see Rule 70.16 and Section 60	report and/or sheets containing rectifications made 7 of the Administrative Instructions under the PCT)
These annexes consist of a	total of Hsheets.	materials (materials (materials PCI)
3. This report contains indica	ations relating to the following it	tems:
I Basis of the repo	ort	
II Priority		
III Non-establishme	ent of report with regard to nove	elty, inventive step and industrial applicability
IV Lack of unity of	importion	aty, inventive step and industrial applicability
KX		
applicability; cit	ent under Article 35(2) with reg ations and explanations supporti	gard to novelty, inventive step or industrial
VI Certain documen	ats cited	-5 own suitairent
VII Certain defects in	n the international application	
	ions on the international applicat	tion
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Date of submission of the demand		c .
	Date of	f completion of this report
17 February 2004 (17.02.2004)	05 April	1 2004 (05.04.2004)
Name and mailing address of the IPEA/US	s	
Mail Stop PCT, Attn: IPEA/US Commissioner for Patents	Authoriz	zed officer
P.O. Box 1450 Alexandria, Virginia 22313-1450	Frank M	M. Lawrence Moull (AUTRIAL
acsimile No. (703) 305-3230	Telephon	ne No. 571-272-0987 De zed officer Lawrence Javanue J
orm PCT/IPEA/409 (cover sheet)(July 199	98)	

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International application No.	
PCT/US03/04941	

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		s of the report
1.	With	regard to the elements of the international application:*
	Щ	the international application as originally filed.
	\boxtimes	the description:
		pages 1-8 as originally filed
1		pages NONE , filed with the demand
	\square	pages NONE , filed with the letter of
	ΙŽ	the claims:
		pages NONE as originally filed
		pages 9-11 , as amended (together with any statement) under Article 19 pages NONE , filed with the demand
		pages NONE , filed with the letter of
	\boxtimes	uie drawings:
		pages 1-2 , as originally filed
1		pages NONE , filed with the demand
		pages NONE, filed with the letter of
		the sequence listing part of the description:
1		pages NONE as originally filed
		pages NONE , filed with the demand pages NONE , filed with the letter of
2	. Wit	
	ame	h regard to the language, all the elements marked above were available or furnished to this Authority in the uage in which the international application was filed, unless otherwise indicated under this item.
1	The	se elements were available or furnished to this Authority in the following language which is:
		the language of a translation furnished for the purposes of international search (under Rule23.1(b)).
		the language of publication of the international application (under Rule 48.3(b)).
	M	the language of the translation furnished for the purposes of international preliminary examination (under Rules
		55.2 and/or 55.3).
3	. Wit	h regard to any nucleotide and/or amino acid sequence disclosed in the international ambigation, the
Ì	inte	mational preliminary examination was carried out on the basis of the sequence listing:
		contained in the international application in printed form.
		filed together with the international application in computer readable form.
ŀ		furnished subsequently to this Authority in written form.
		furnished subsequently to this Authority in computer readable form.
		The statement that the subsequently furnished written sequence listing does not go beyond the disclosure in the
1		international application as filed has been furnished.
		The statement that the information recorded in computer readable form is identical to the written sequence listing has been furnished.
4	. 🖂	The amendments have resulted in the cancellation of:
		the description, pages NONE
		the claims, Nos. 14-18
İ		the drawings, sheets/fig NONE
5	. 🔲	This report has been established as if (some of) the amendments had not been made, since they have been considered to as
		beyond the disclosure as filed, as indicated in the Supplemental Box (Rule 70.2(c)) **
14	Repla is ren	cement sheets which have been furnished to the receiving Office in response to an invitation under Asia Language
		ort as "originally filed" and are not annexed to this report since they do not contain amendments (Rules 70.16 and 70.17). replacement sheet containing such amendments must be referred to under item 1 and annexed to this report.
L		o mus report.

INTERNATIONAL PRELIMINARY EXAMINATION REPORT

Form PCT/IPEA/409 (Box V) (July 1998)

International application No. PCT/US03/04941

STATEMENT	·		
Novelty (N)	Claims	1-13	, NAT
		NONE	YE
Inventive Step (IS)	Clatere	4.40	
(15)	Claims Claims	NONE	YE
			NC
Industrial Applicability (IA)	Claims		YI
	Claims	NONE	N
NEW CITATIONS			

-9-CLAIMS



What is claimed is:

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1. A sorption concentrator for removing contaminants from a gas stream, comprising:

a plurality of adjacent generally rectangular sorption units;

a gas flow system directing gas to be cleaned through a majority of said plurality of sorption units during a sorption cycle and directing a separate clean gas stream through the remaining sorption units during a desorb cycle;

said plurality of adjacent sorption units each including an integral semi-conductive foil substrate formed of a plurality of semi-conductive foil elements including parallel convoluted surfaces and parallel channels extending generally parallel to a direction of flow of said gas to be cleaned during said sorption cycle and said clean gas stream during said desorption cycle extending from an inlet to an outlet of said sorption units conductively bonded together to form an integral semi-conductive substrate coated with a sorption material; and

a source of electrical current connected to said semi-conductive foil substrate rapidly resistively heating said remaining sorption units during said desorption cycle.

- 2. The sorption concentrator as defined in Claim 1, wherein said integral semiconductive foil substrate is formed of aluminum foil.
- 3. The sorption concentrator as defined in Claim 2, wherein said aluminum foil substrate has a thickness between 0.005 mm and 2 mm.
- 4. The sorption concentrator as defined in Claim 1, wherein said aluminum foil substrate has a thickness of between 0.005 mm and 2 mm.
- 5. The sorption concentrator as defined in Claim 2, wherein said aluminum foil substrate has a thickness of between 0.05 mm and 1 mm.

[Replacement Sheet]

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- 6. The sorption concentrator as defined in Claim 2, wherein said aluminum foil substrate has a thickness of between 0.1 mm to and 0.3 mm.
- 7. The sorption concentrator as defined in Claim 1, wherein said integral semiconductive foil substrate comprises a honeycomb formed of a plurality of generally

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parallel corrugated semi-conductive foil sheets each conductively bonded in electrical contact to a generally planar semi-conductive base sheet and coated with a sorption material.

- 8. The sorption concentrator as defined in Claim 1, wherein said integral semi-conductive foil substrate comprises a plurality of parallel semi-conductive foil tubes conductively bonded together in electrical contact formed of a semi-conductive foil coated with a sorption material extending parallel to said direction of flow of said gas to be cleaned during said sorption cycle and parallel to said clean gas stream during said desorb cycle.
- 9. The sorption concentrator as defined in Claim 1, wherein said sorption material is selected from the group consisting of activated carbon, zeolite and porous polymers bonded to said semi-conductive foil substrate.

Please cancel Claims 10 through 18.

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10. (New) A method of removing contaminants from a gas stream, comprising the following steps:

forming a plurality of generally rectangular sorption units by forming a plurality of separate semi-conductive foil elements including parallel convoluted surfaces, conductively bonding said semi-conductive foil elements together forming an integral semi-conductive foil substrate having a plurality of parallel channels extending from an inlet to an outlet of said sorption units and coating said integral semi-conductive foil substrates with a sorption material;

directing a stream containing contaminants through said parallel channels of a plurality of said sorption units, wherein said sorption material collects said contaminants; and

applying an electric current to said integral semi-conductive foil substrate of at least one of said sorption units, thereby rapidly heating said integral semi-conductive foil substrate of said one of said sorption units and simultaneously directing clean air through said one of said sorption units, thereby desorbing said contaminants during a desorption cycle.

11. (New) The method of removing contaminants from a gas stream as defined in Claim 10, wherein said method includes coating said semi-conductive substrate with a sorption material by dipping said integral semi-conductive substrate in a slurry of sorption

[Replacement Sheet]

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material, removing said integral semi-conductive foil substrate from said slurry and drying said coating of sorption material on said semi-conductive foil substrate.

- 12. (New) The method of removing contaminants from a gas stream as defined in Claim 10, wherein said method includes forming a plurality of separate semi-conductive foil elements from an aluminum foil.
- 13. (New) The method of removing contaminants from a gas stream as defined in Claim 10, wherein said method includes forming said plurality of separate semi-conductive foil elements from a semi-conductive foil having a thickness of between 0.005 mm and 2 mm.

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[Replacement Sheet]